



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

MODIFIED TRANSFER FUNCTION DEPOSITION
BAFFLES AND HIGH DENSITY PLASMA IGNITION
THEREWITH IN SEMICONDUCTOR PROCESSING

Application Number: 10/080496
Confirmation Number: 8492
First Named Applicant: Jozef Brcka
Attorney Docket Number: TAZ213
Art Unit: 1763
Examiner: Luz L.
Search string: (6287435).pn.



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Certification: This Information Disclosure Statement was submitted under the following conditions, which satisfies the requirement under 37 CFR 1.97(e). The filer certified:

That each item of information contained in the information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6287435	2001-09-11	Drewery et al.			

Signature

Examiner Name	Date



1763

Electronic Filing System (EFS) Data
Electronic Patent Application Submission
USPTO Use Only

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EFS ID: 45389
Application ID: 10080496
Title of Invention: MODIFIED TRANSFER FUNCTION
DEPOSITION BAFFLES AND HIGH
DENSITY PLASMA IGNITION
THEREWITH IN SEMICONDUCTOR
PROCESSING
First Named Inventor: Jozef Brcka
Domestic/Foreign Application: Domestic Application
Filing Date: 2002-02-22
Effective Receipt Date: 2003-08-12
Submission Type: Information Disclosure
Statement
Filing Type:
Confirmation number: 8492
Attorney Docket Number: TAZ213



Total Fees Authorized:

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Title of Invention	MODIFIED TRANSFER FUNCTION DEPOSITION BAFFLES AND HIGH DENSITY PLASMA IGNITION THEREWITH IN SEMICONDUCTOR PROCESSING									
<p>Application Number: 10/080496 </p> <p>Date: 2002-02-22</p> <p>First Named Applicant: Jozef</p> <p>Confirmation Number: 8492</p> <p>Attorney Docket Number: TAZ213</p>										
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<table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Joseph R. Jordan Registered Number: 25,686</td><td>Joseph R. Jordan</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Joseph R. Jordan Registered Number: 25,686	Joseph R. Jordan	Attorney		
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Joseph R. Jordan Registered Number: 25,686	Joseph R. Jordan	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>TAZ213-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	TAZ213-usidst.xml		us-ids.dtd		us-ids.xsl
Documents being submitted	Files									
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Comments										